

The Nanoworkbench

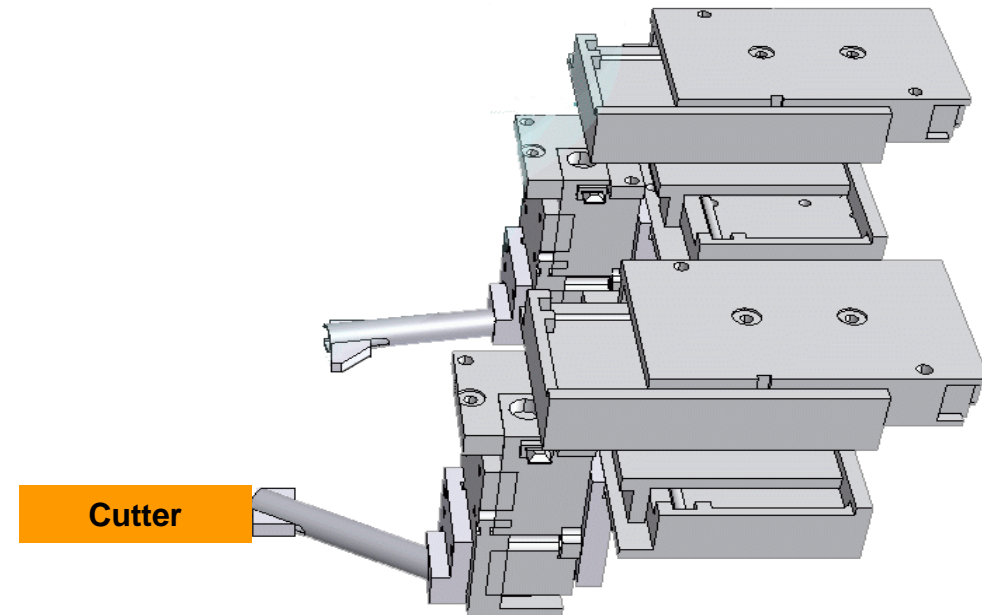
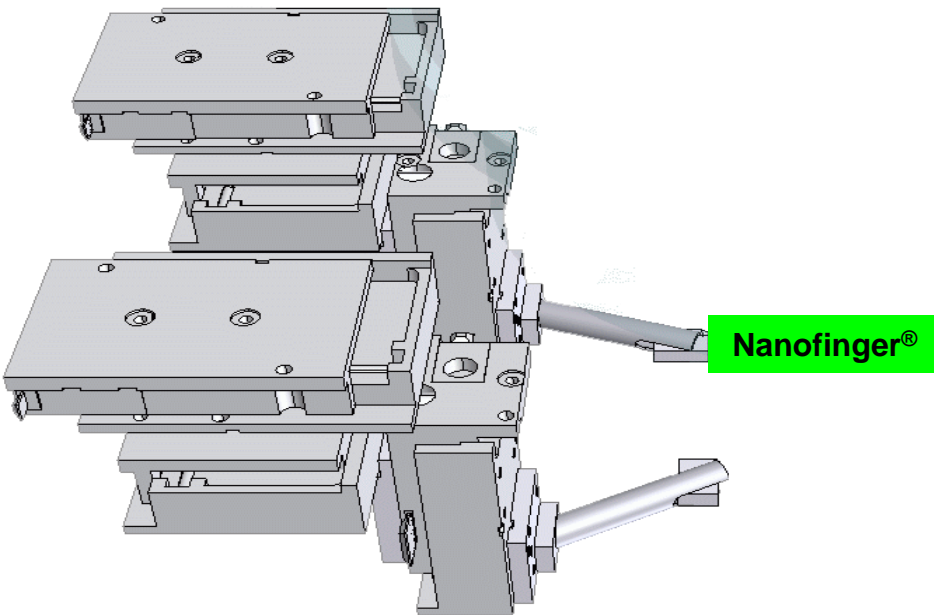
Standard Application Packages

NanoCutting:

***Nano-Cutting of structures inside
SEM/FIB systems with
the Nanoworkbench
from Klocke Nanotechnik***

NanoCutting

Nanoworkbench Configuration:

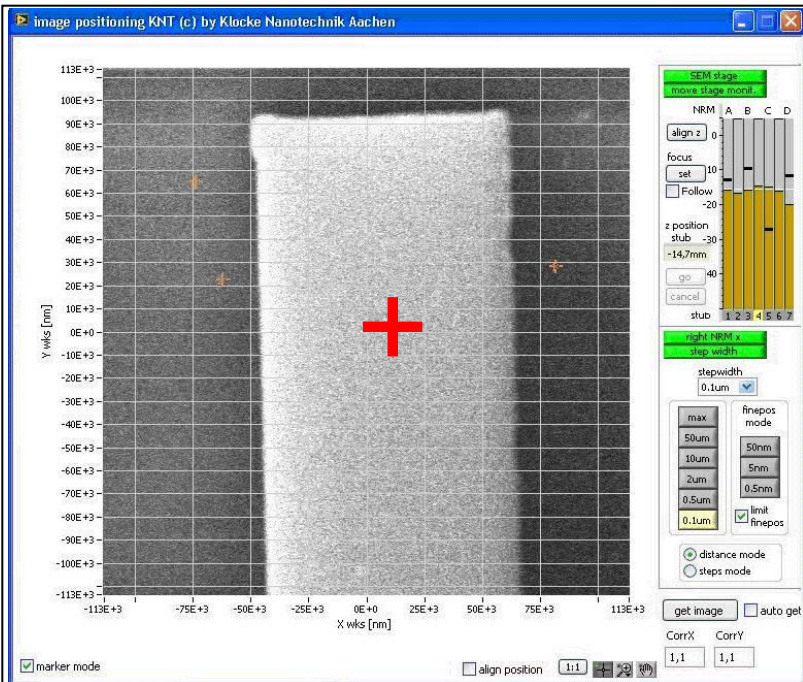


1. Nanomanipulator equipped with: 1D-Nanofinger® as Scout
 2. Nanomanipulator equipped with: Cutting/Milling or Slicing tool (diamond or metal)
- Standard Software Package: Macro Executor, Live Image Positioning, Assistants, Sequencer

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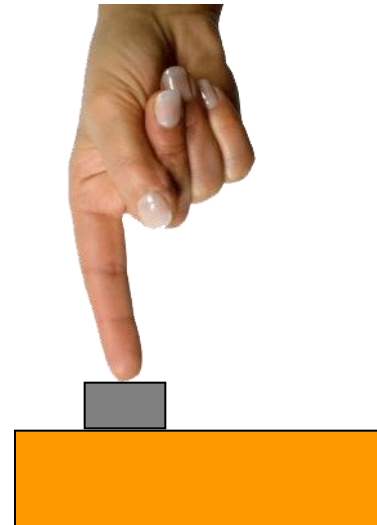
NanoCutting

Operation Sequence



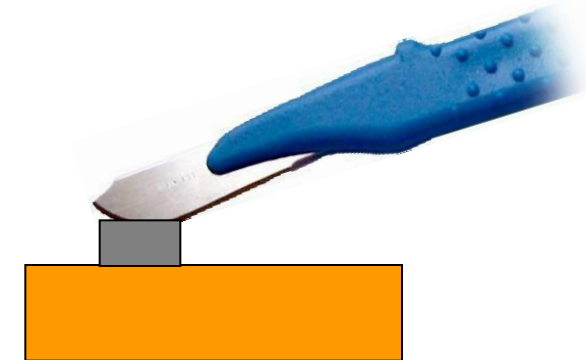
Live Image Positioning:

Select target, define structures



1D-Nanofinger®:

finds target



Cutter:

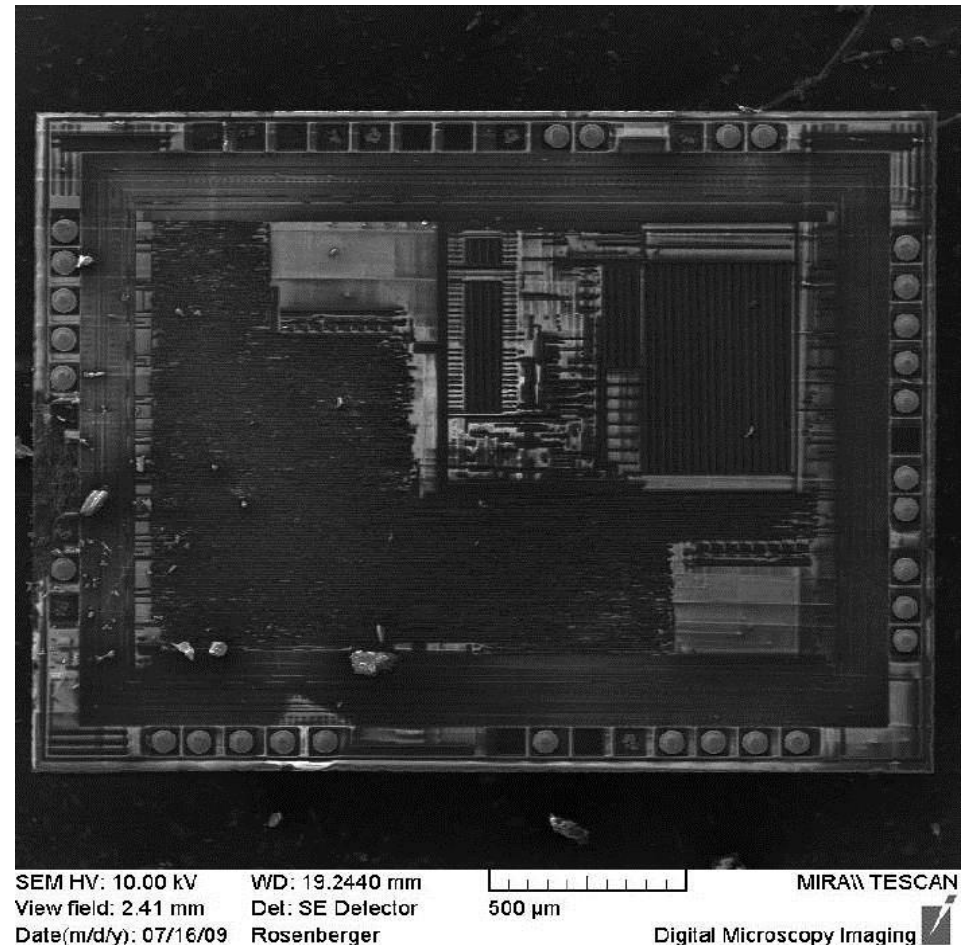
prepares structures

Cutting a conductor path on a semiconductor chip

- On a semiconductor chip are several strip lines
- Cutting of a conductor is sometimes necessary, e.g. for measurements
- A nanorobotic manipulator from Klocke Nanotechnik with a cutting tool is used for precise cutting on a semiconductor chip
- The thickness of the Al conductor is < 200 nm
- Preparation for cutting is done within minutes
- Cutting itself not more than 2 min

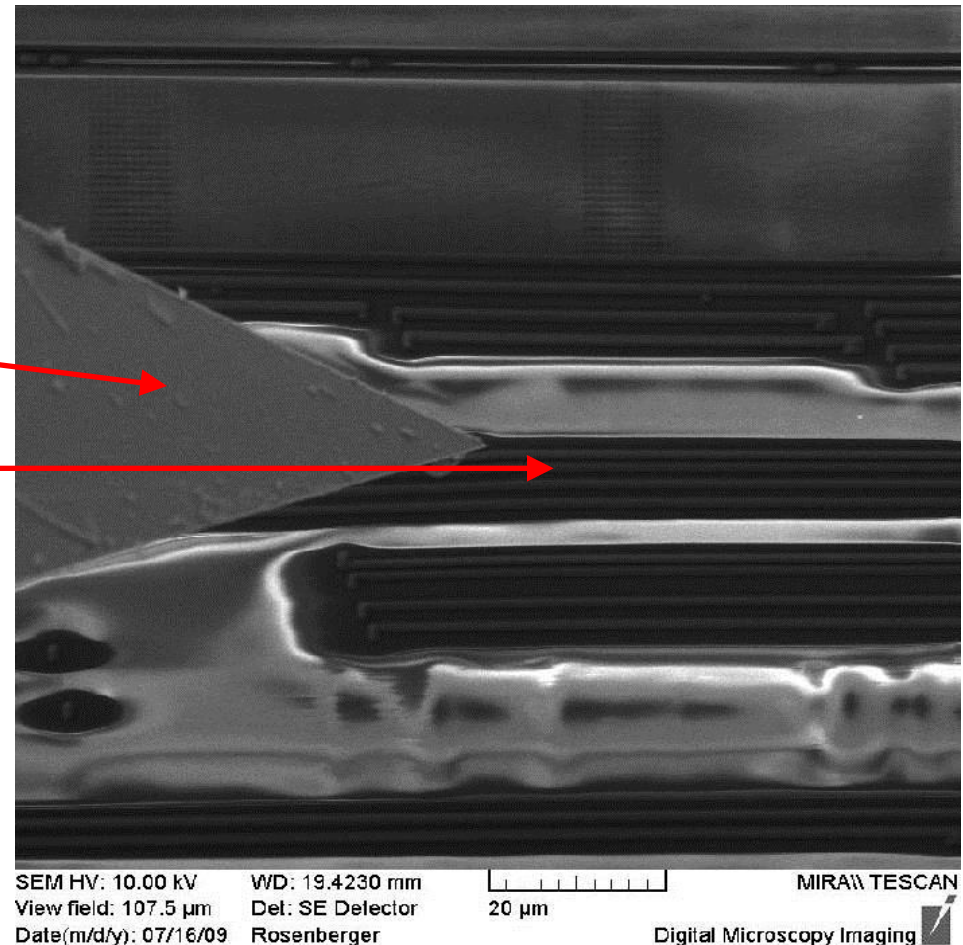
The chip with several strip lines

- Overview



**The cutting tool nearby
the selected conductor
before cutting**

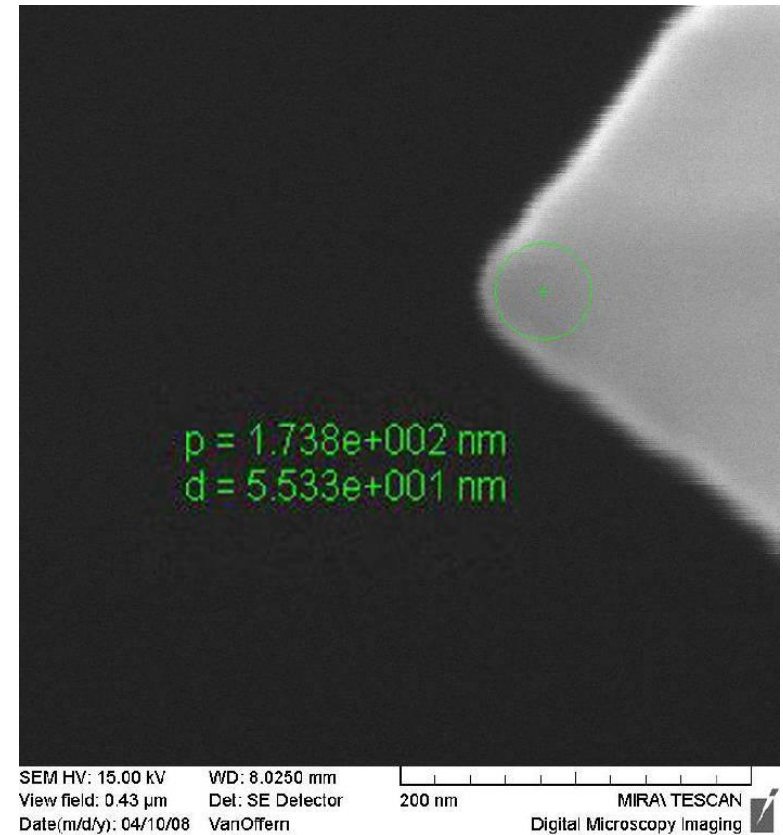
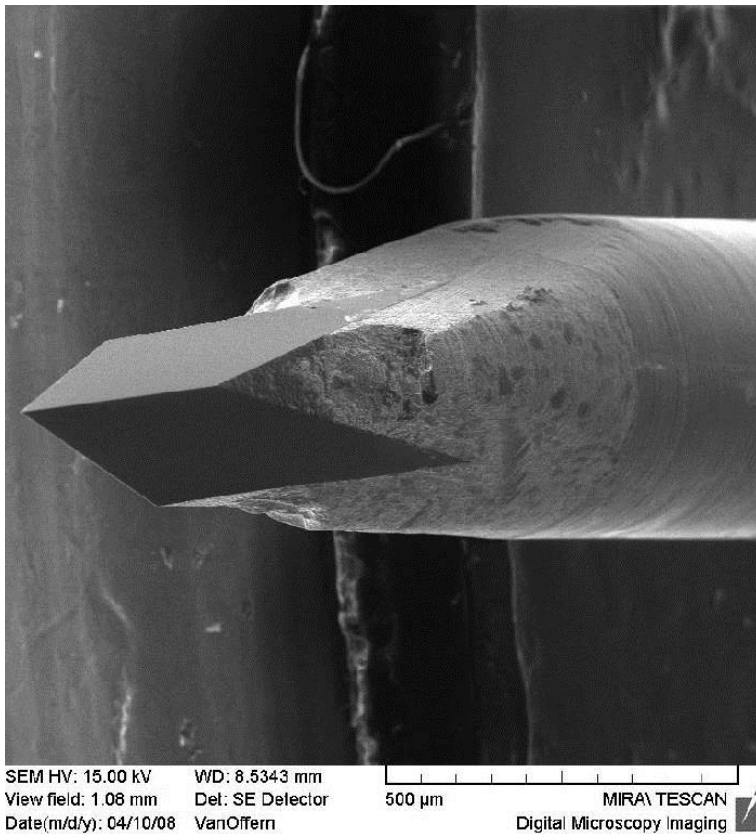
- Cutting tool
- Conductor before cutting



NanoCutting

Cutting Tool

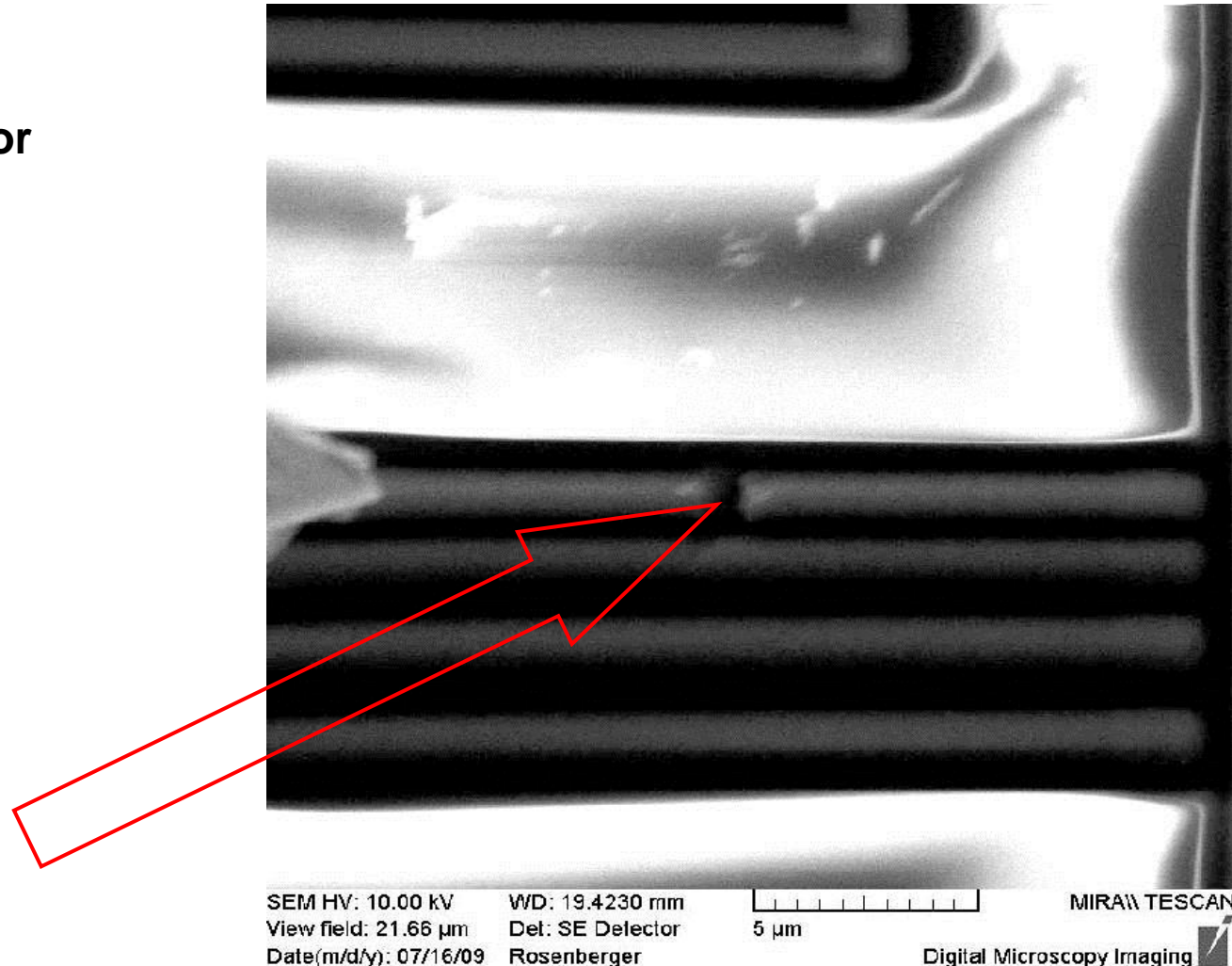
Cutting edge diameter = 55 nm



Cutting strip lines

After cutting the conductor

- Cutting process needs about 2 min
- **Circuit editing without ion beam!**



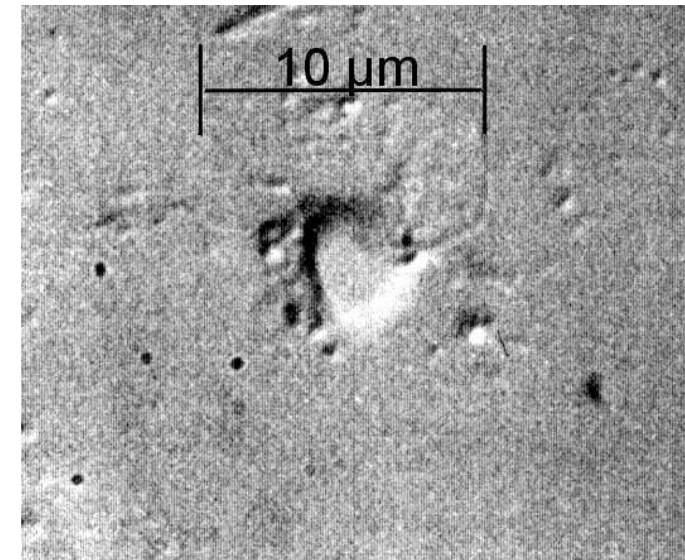


NanoCutting

Nano-Jackhammer Module

Nano-Jackhammer:

- With tool tip accelerations of more than 50 G
- Programmable step amplitudes
- Nano - Jackhammer mode by periodic accelerations

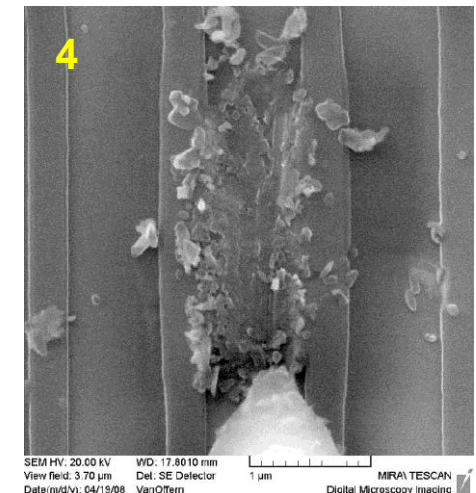
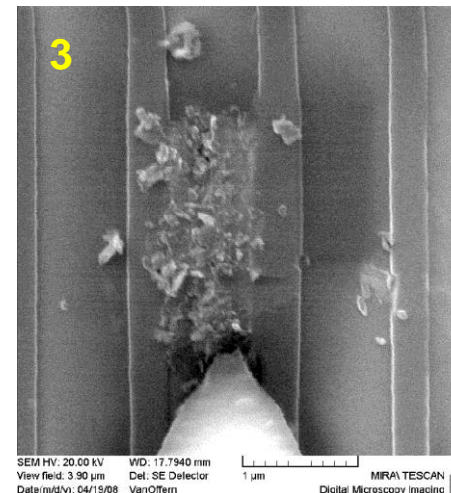
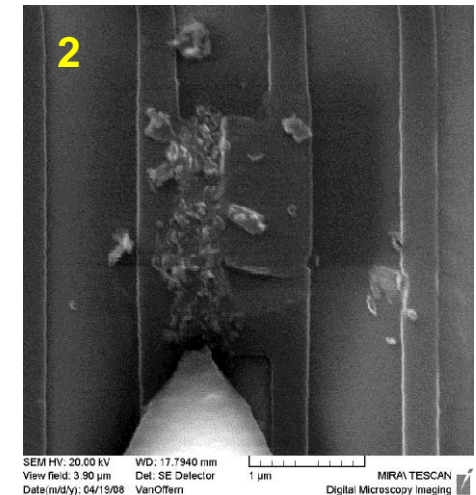
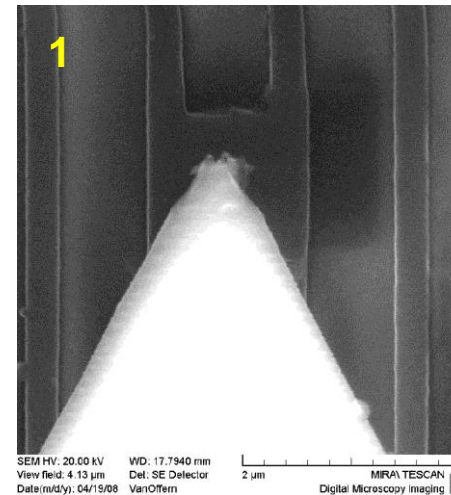


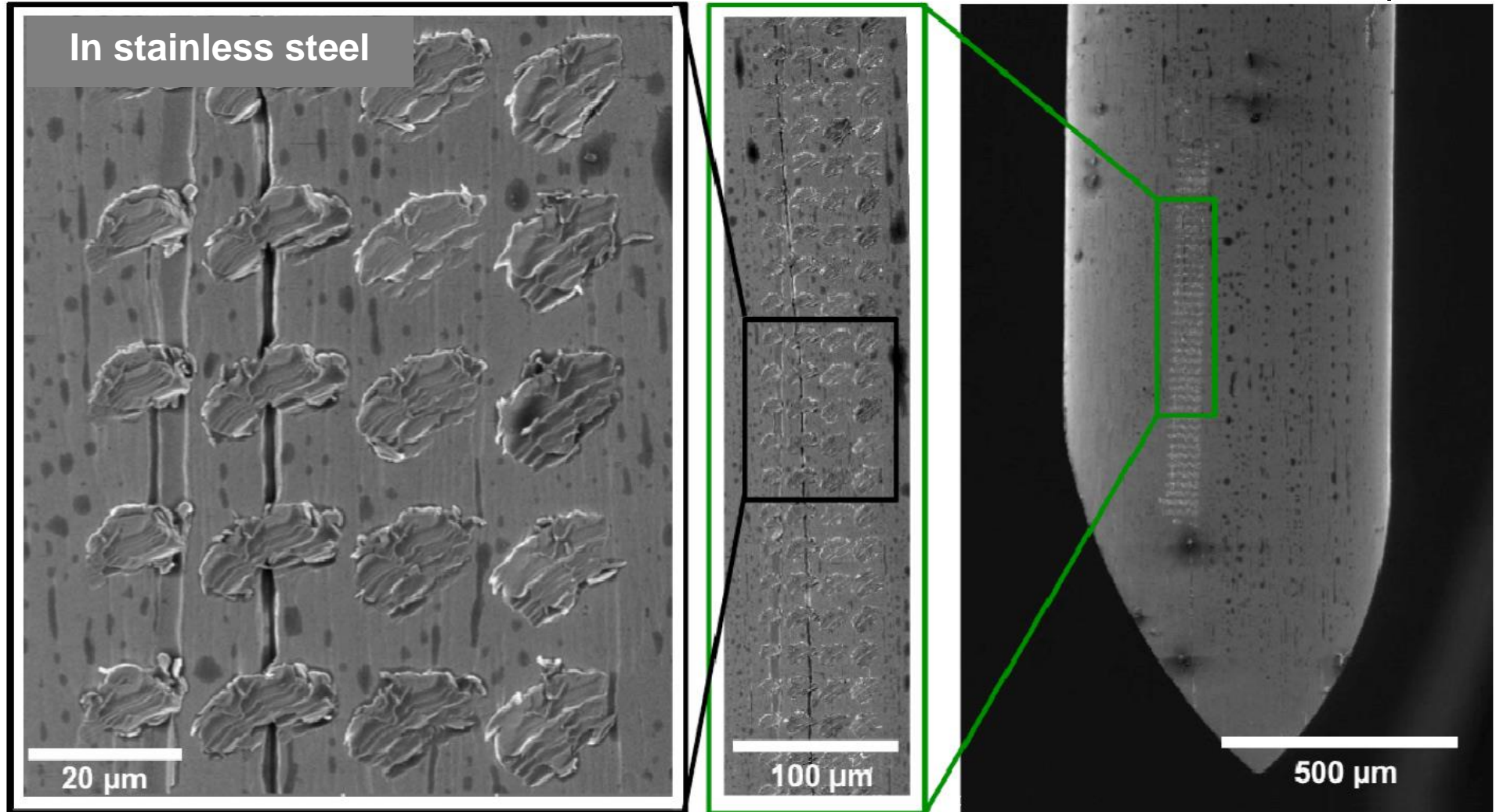
Tip imprint into diamond,
diameter = 6 microns

Nano-Jackhammer Module

Nano-Jackhammer module

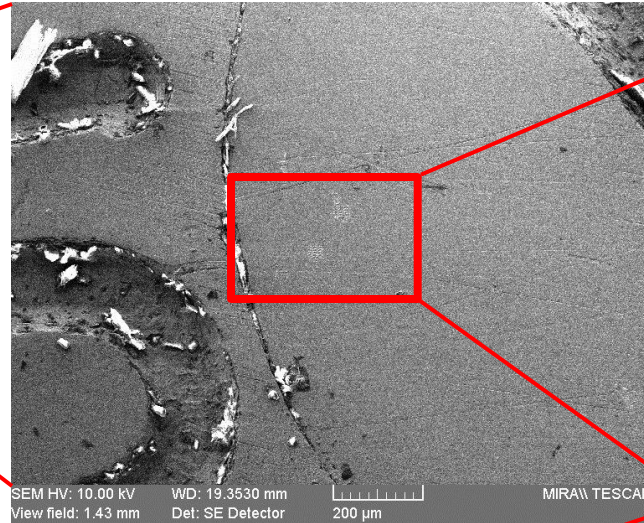
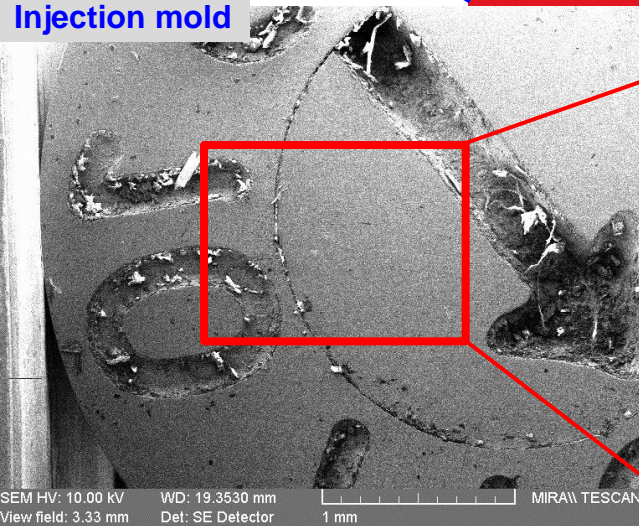
- Cutting of a **hard ceramic** sample on coarse scale:
- 4 “Jackhammer-lines” are sufficient to cut down to the substrate
- Much faster than FIB



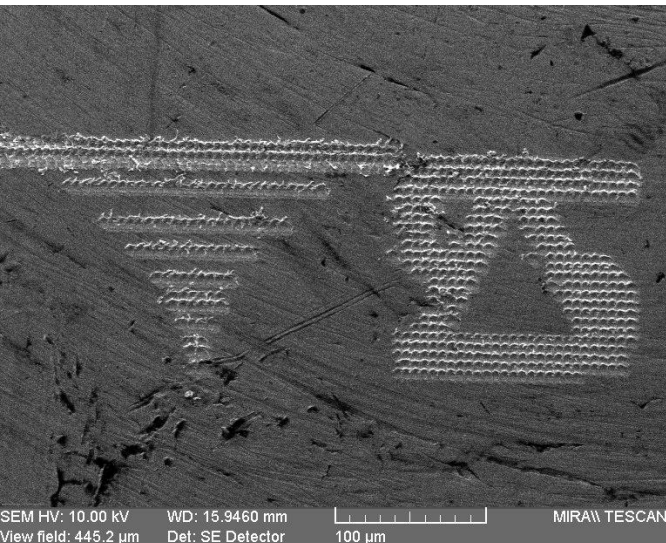
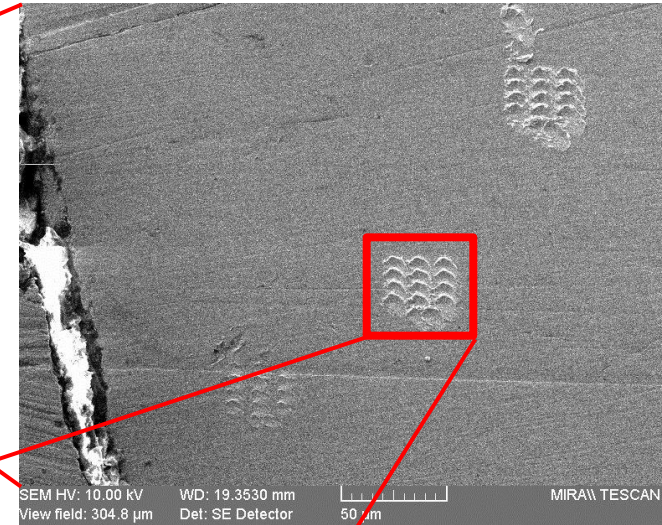


Plastic Bottles

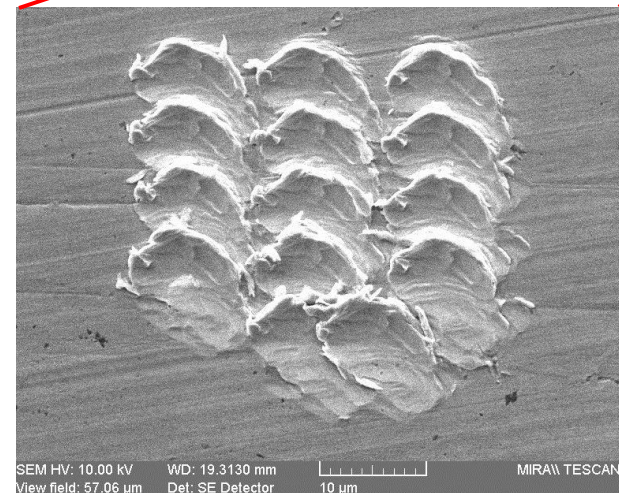
Injection mold



Nano-Imprints



**Hidden Logos
against piracy of
products**

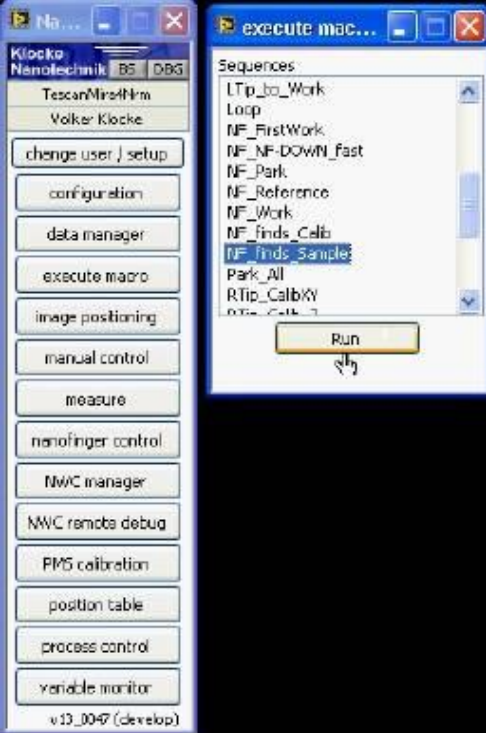


Application Note



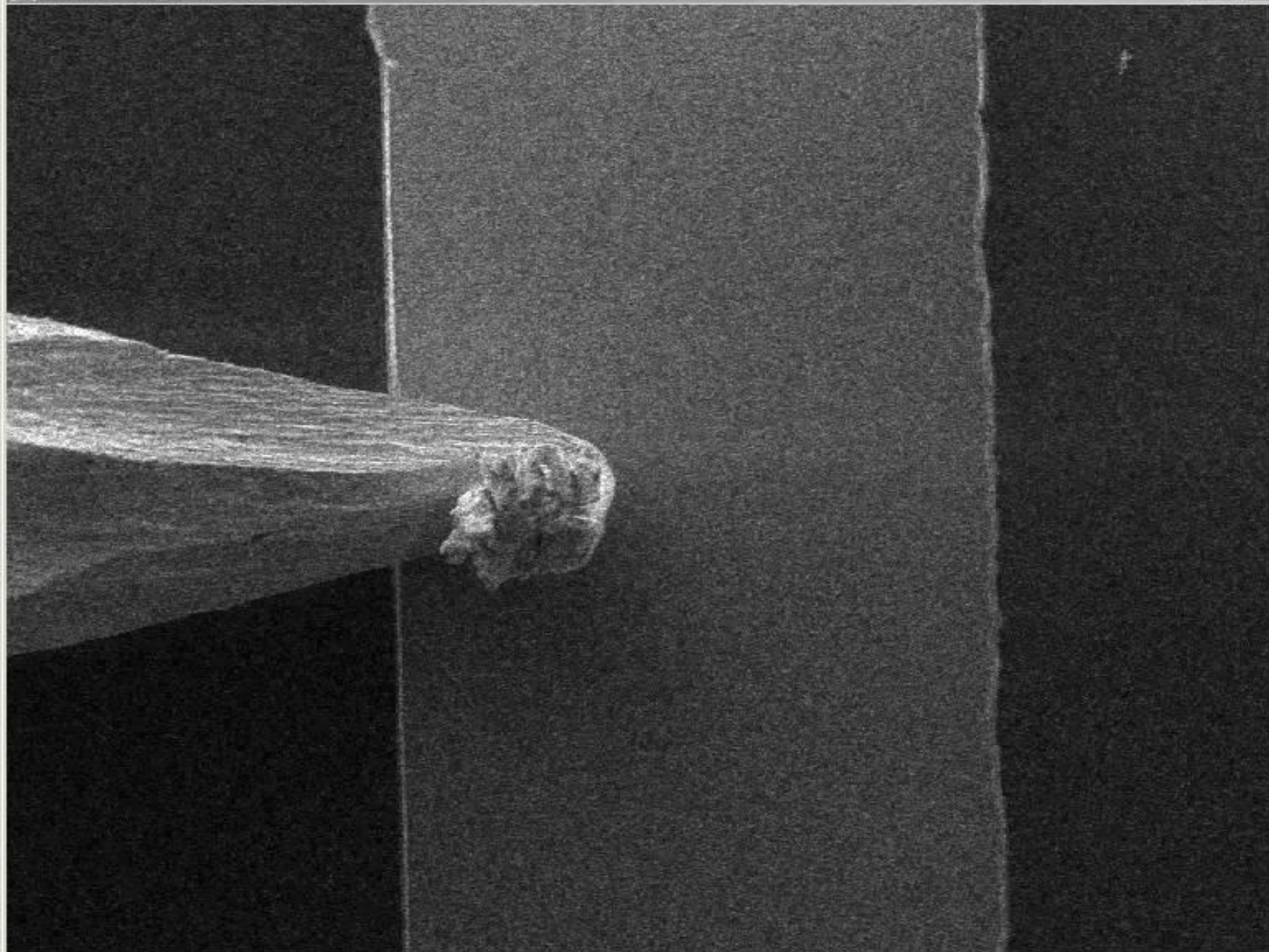
Nano-Milling in Silicon

***Nano-Milling of structures with
the Nanoworkbench
from Klocke Nanotechnik***



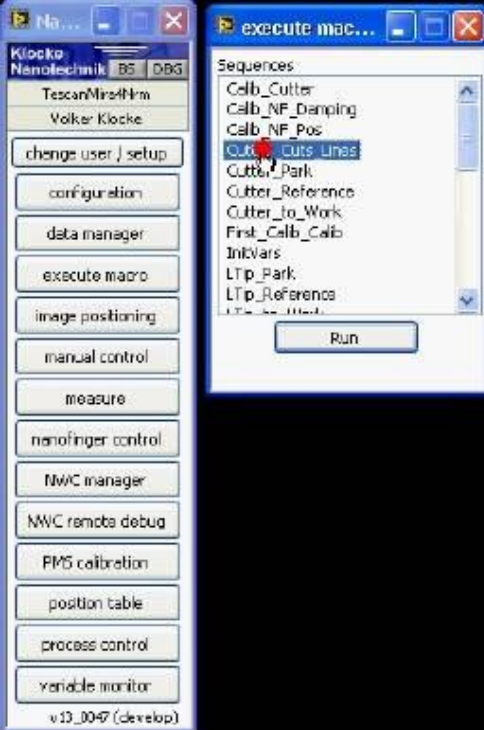
**NanoControl
Macro:**

**Nanofinger
finds sample**



**SEM –
image**

**Nanofinger
removal**



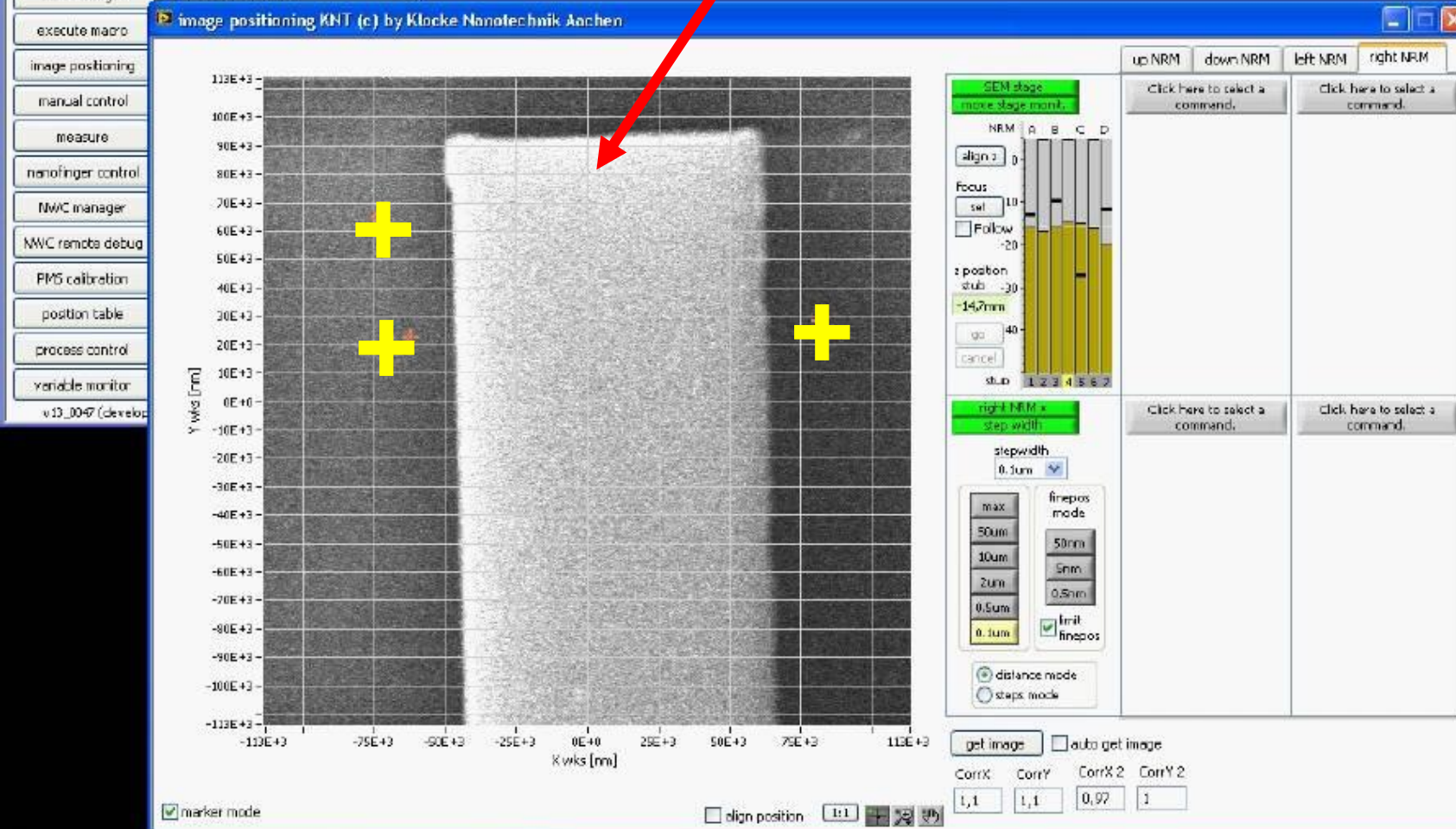
**NanoControl
Macro:**

**Select process
Cutter_Cuts_Lines**



Live Image Positioning Module

NanoControl

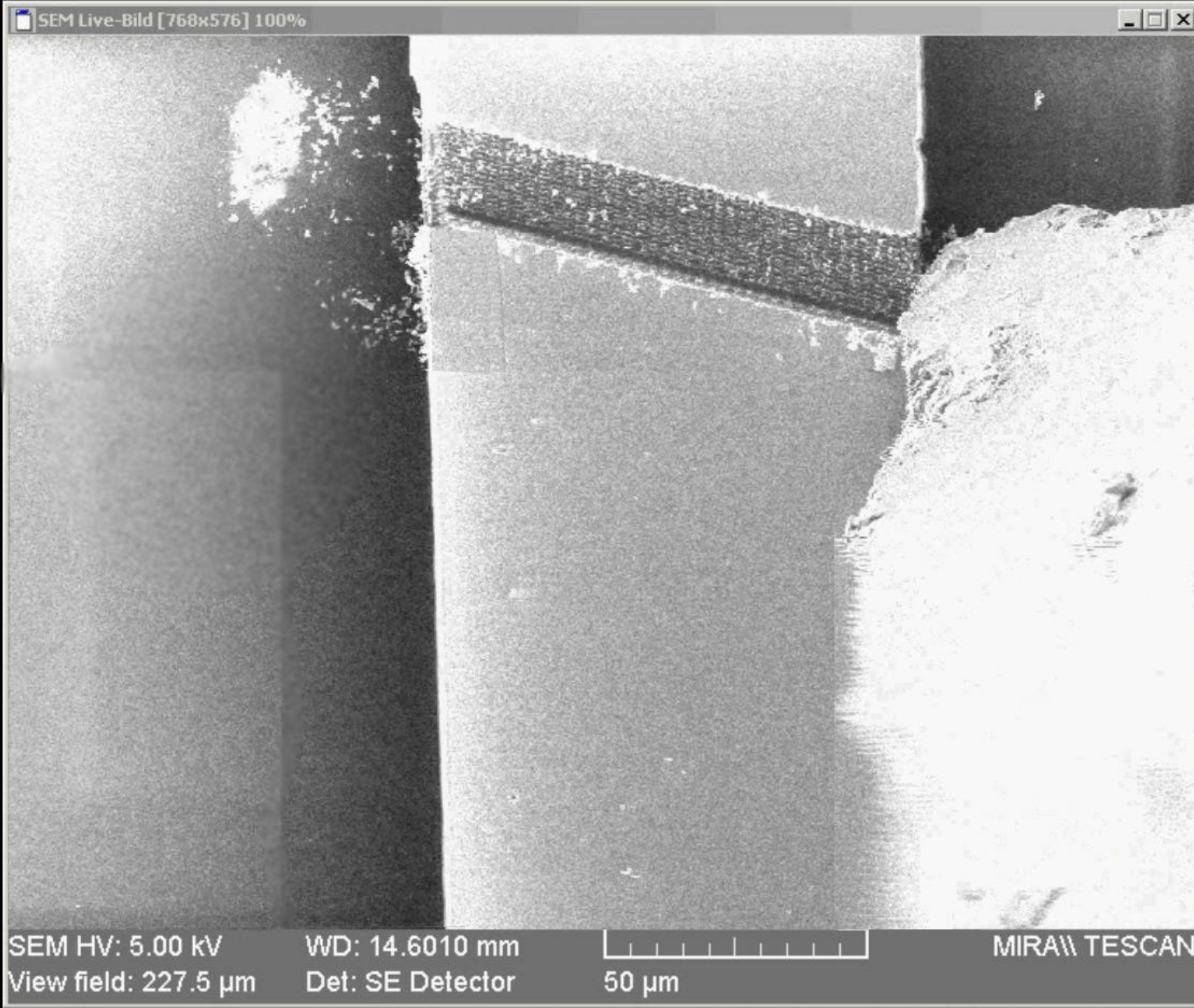


Wizard:

Mark Start
and End
of Line

plus one
marker for
Line-Array
Width





**SEM –
image**

**Nano-Milling
in
Silicon**

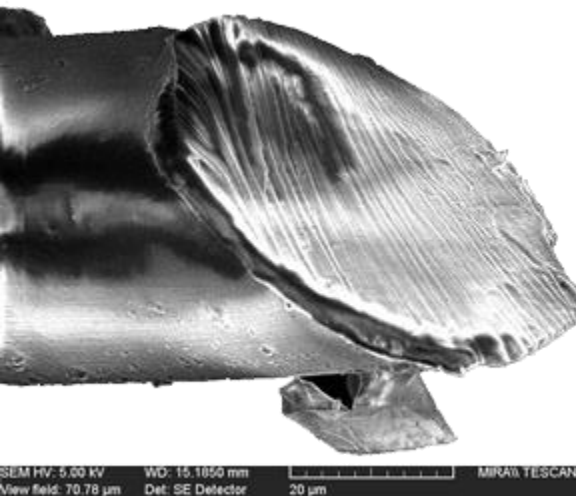
**2 seconds
per line,
about 900
times
faster
than
FIB**

Application Note



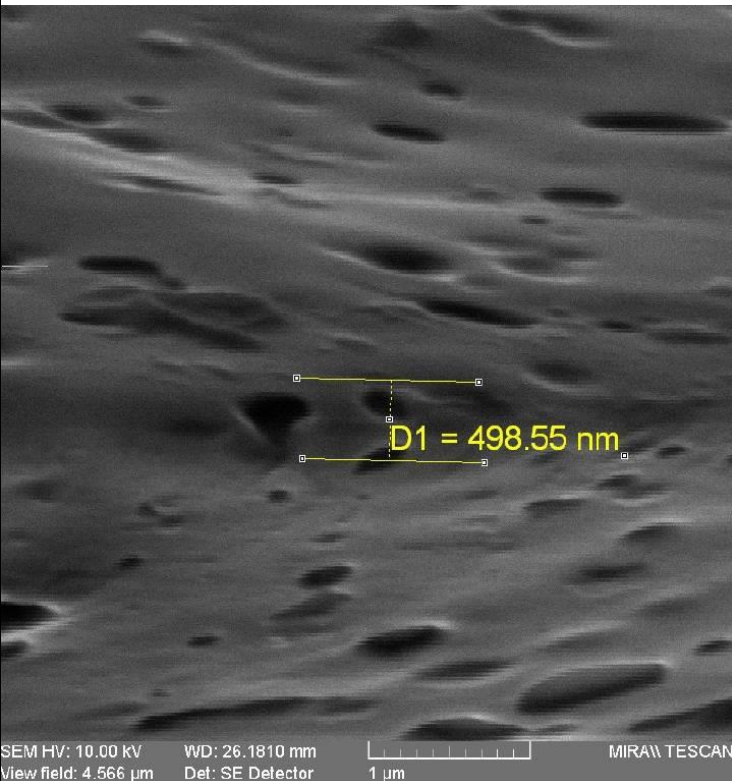
NanoSlicing of Textile Wires

***Nano-Slicing of structures with
the Nanoworkbench
from Klocke Nanotechnik***



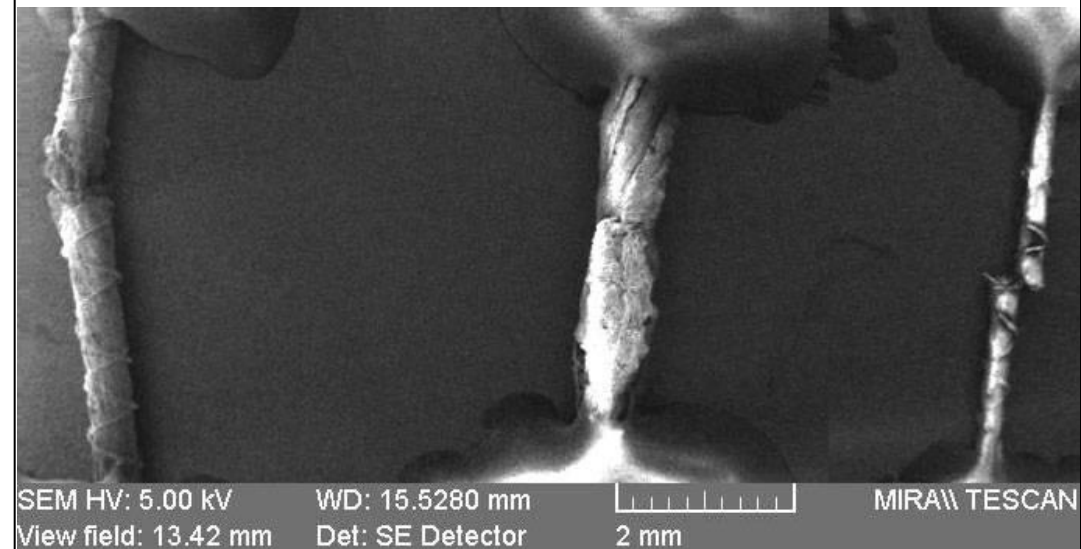
The Tool:

A cutter sharper than 500 nm:



The samples:

Textile wires with different diameter, material and nano-structure



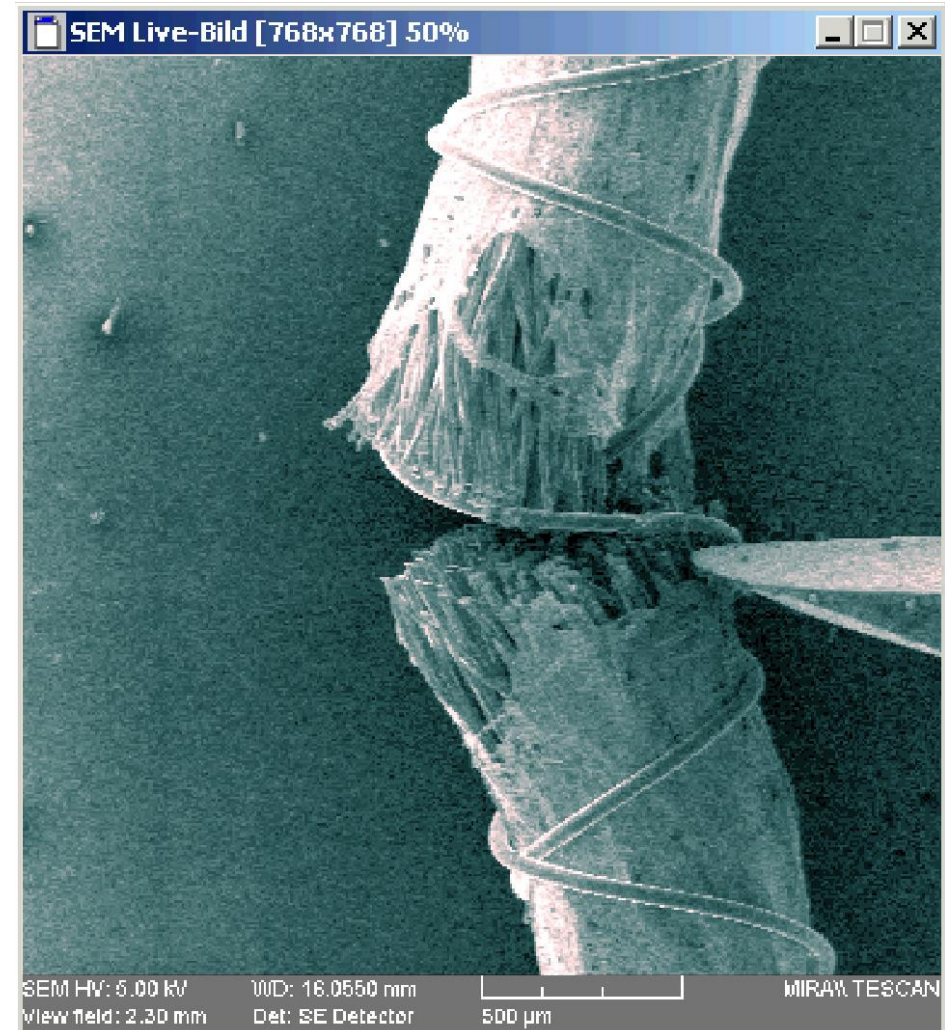
Application Note NanoSlicing

Slicing a sample

The automatic Slicing process: *

- A slicing algorithm was selected out of a set of options

* realized by Cartesian manipulator and simple process teaching

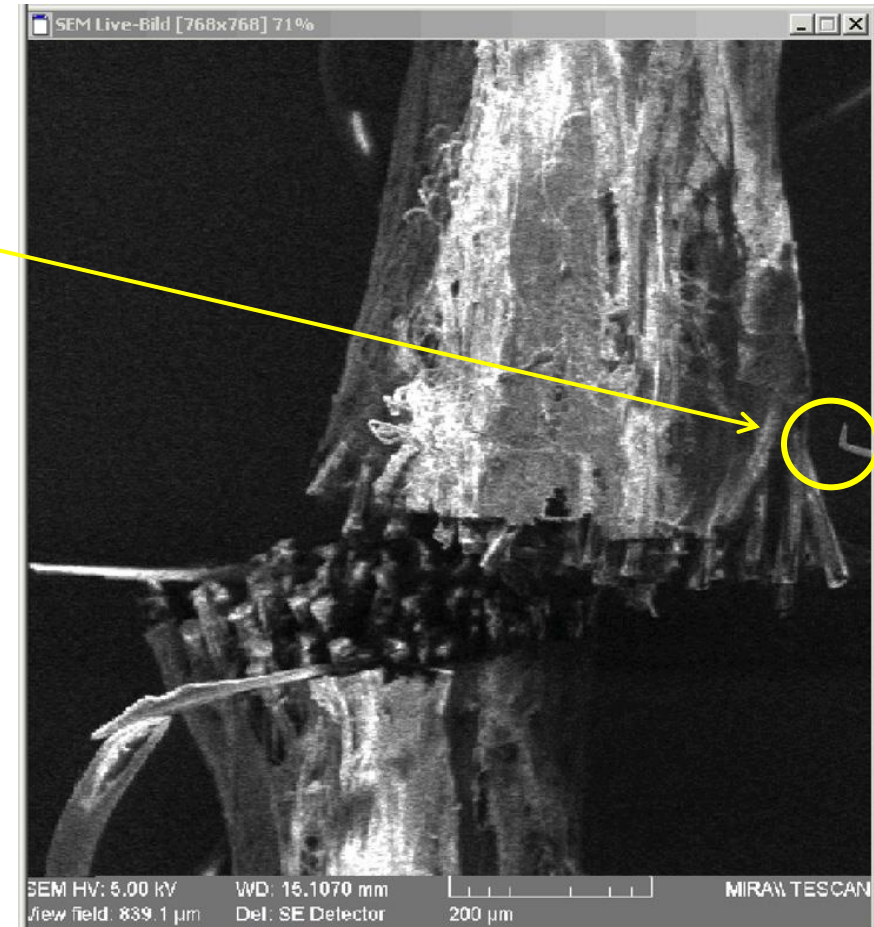


Application Note NanoSlicing

Digging into the sample

Inspection after slicing, now by digging into the sample:

- A needle with a small hook intrudes the sample and grabs the fibers
- The bundle is fanned out allowing to walk into the internal structures with the SEM images.
- Also the outer cleaving can be visualized from its inner side.

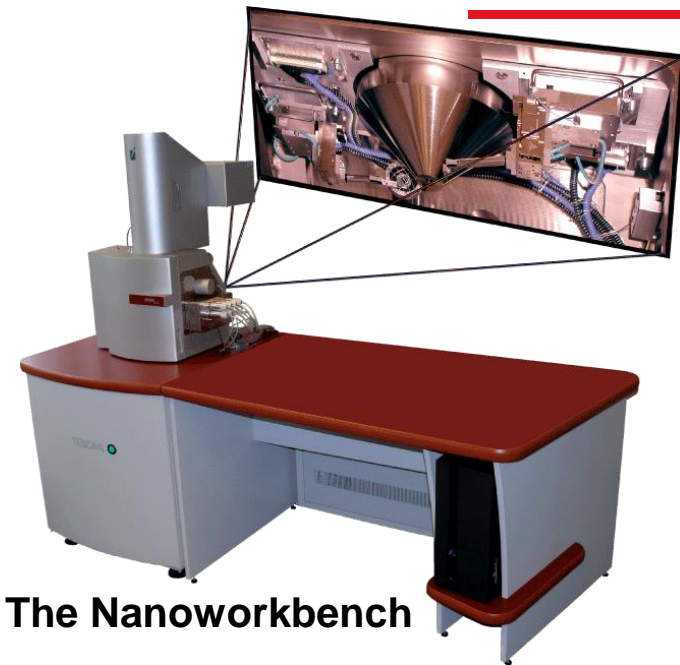


Summary

- With the Nanoworkbench from Klocke Nanotechnik cutting of material on fine and coarse scale is very fast and easy.
- The Live Image Positioning module allows to direct the cutting tool in XY to the target area just by mouse-click into the SEM image.
- The Nanofinger® operating as Scout allows a fast and secure automatic approach of the cutting tool to the sample, also on isolators.
- Automatic macros and absolute positioning in superior precision allow to program the cutting mode, range and areas.

The Nanoworkbench

and its Application Packages



NanoCutting ...

is one out of several “Standard Application Packages” of our [Nanoworkbench](#).

The Nanoworkbench enables the hand-eye coordination as used at Light Microscopes now in any SEM/FIB, together with automation of the SEM/FIB (@ZEISS, FEI, TESCAN)



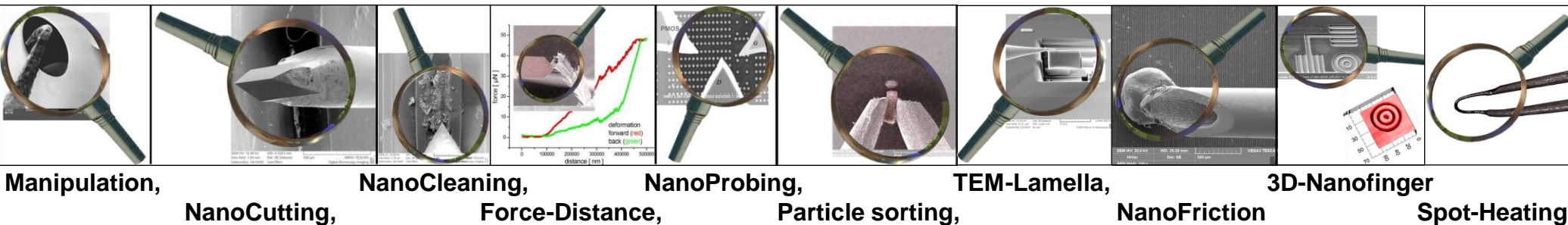
At Light Microscopes it is natural for everybody to use tool sets like tweezers, knives, hooks, probes and several different measurement tools, so it is with the Nanoworkbench.

The Nanoworkbench

One Product for all applications

The Nanoworkbench Standard Packet includes:

- The basic application package “Nanomanipulation” and
- one additional “Application Package” out of:



Each application package includes a standard tool, a standard sample and pre-defined processes as source-code and origin for own projects.

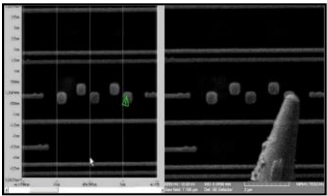
- The following set of modules for easy usage an application control:

The Standard Packet

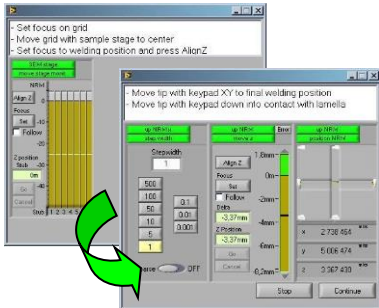
Hand-eye coordination:



Nanofinger® as Scout, guiding the
Nanoworkbench Tools,

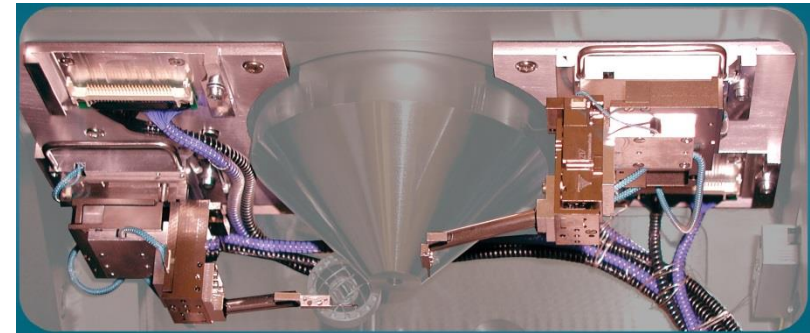
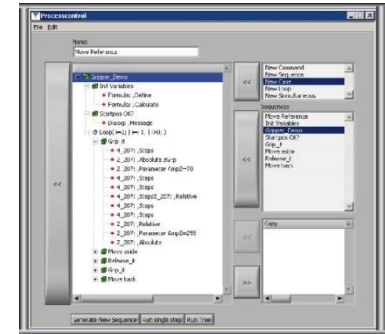


Live Image Positioning,



Assistants
(Wizards),

Sequencer for automation,
Macro Executor,
Remote Control,
...



2 Nanorobotics Manipulators
with docking stations

More information?

Please ask for the leaflet “Nanoworkbench”

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